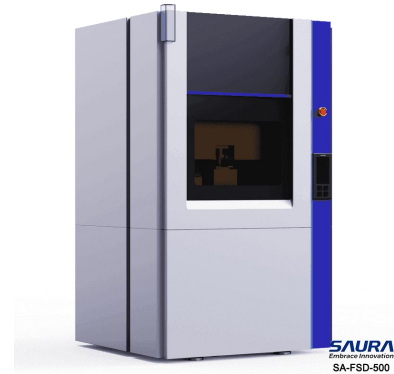


Femtosecond Laser 3D Micro-Nano Processing Equipment for Hard-and-Brittle Materials

Model: SA-FSD-500

SA-FSD-500 Femtosecond Laser 3D Micro-Nano Processing System adopts material modification technology to fabricate intricate patterns inside hard-and-brittle materials. It is well-suited for the preparation of 2D and 3D waveguide structures.



Feature

- Femtosecond processing
- Micro-holes and micro-grooves
- Material modification
- High-consistency processing

Application

- Low-loss waveguide fabrication
- Waveguide end-face profile control
- Processing with arbitrary 3D vector path, energy and velocity modulation
- Supports fabrication of multiple grating types

Specifications:

Parameter	Descriptions
Processing Position	Patterned material modification and waveguide structures
Wavelength	1030nm/515nm
Objective Lens	50×/20×
Illumination	Reflection & Transmission
Functional Configuration	External energy adjustment, 2D motorized slit
Optional	Spatial Light Modulator (SLM), auto-focus tracking
Adjustment Stage	Manual
Travel Range of Motion Stage	200 mm × 200 mm
Fixture & Workstation	Large-area transparent adsorption stage

Software & Processing Capabilities:

- 1.Support two processing modes: constant-speed processing and pulse-position triggered processing.
- 2.Support 3D vector processing for arbitrary paths.
- 3.Support speed modulation and energy tuning within the processing path.
- 4.Support script-programmed processing.
- 5.Support processing with imported graphics.
- 6.Support graphic-drawing-based processing via the camera interface.